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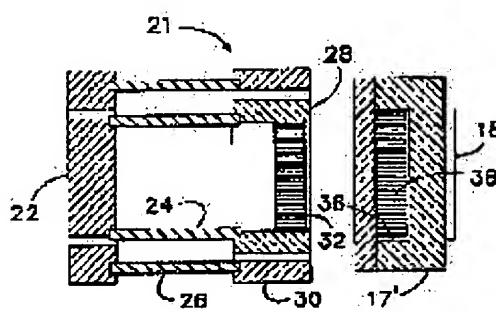
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(54) TWO-DIMENSIONAL POSITION ADJUSTING DEVICE

(57)Abstract:

PURPOSE: To provide the two-dimensional position adjusting device which can two-dimensionally move a sample to be tested over a wide range while compensating temperature drift.

CONSTITUTION: The sample to be tested is held on a surface by a sample holder 17'. A movable supporter 21 is provided with a pair of PZT coaxial tubes 24 and 26 fixed on a base, and one inside coaxial tube of a pair of these PZT coaxial tubes is provided with a magnetic means 32 for magnetically supporting the sample holder. A control signal to be supplied to a pair of PZT coaxial tubes in this movable supporter 21 is adjusted, and the position of the sample holder is two-dimensionally adjusted. Thus, the position of the sample to be tested at an SMT (scanning tunnel microscope) can be adjusted with high accuracy over the wide range on a two-



dimensional X-Y plane to a probe chip.

LEGAL STATUS

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